



PATENT
Atty. Docket No.: SSI-02001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#9/Amend A
Q Free
11/12/02

In re Application of)

Group Art Unit: 2825

Maximilian A. Biberger)

Examiner: Caridad Everhart

5 Serial No. 09/841,800)

Filed: April 24, 2001)

**AMENDMENT AND RESPONSE TO
OFFICE ACTION MAILED ON
JULY 29, 2002**

10 For: **METHOD FOR DEPOSITING
METAL FILM AND METAL
DEPOSITION CLUSTER TOOL
INCLUDING SUPERCRITICAL
DRYING/CLEANING MODULE**)

162 North Wolfe Road
Sunnyvale, CA 94086
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15 Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

20 **AMENDMENTS**

Please amend the Application as follows:

In the Claims:

25 Please amend the claims as follows (clean version of amended claims):

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1 19. (Amended) A method of depositing a film on a substrate comprising the steps of:
2 maintaining supercritical carbon dioxide from a first module in contact with the
3 substrate to remove a sorbate selected from the group consisting of an absorbate
4 and an adsorbate from the substrate, thereby forming a desorbed substrate; and

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01 FC:1202
02 FC:1201

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